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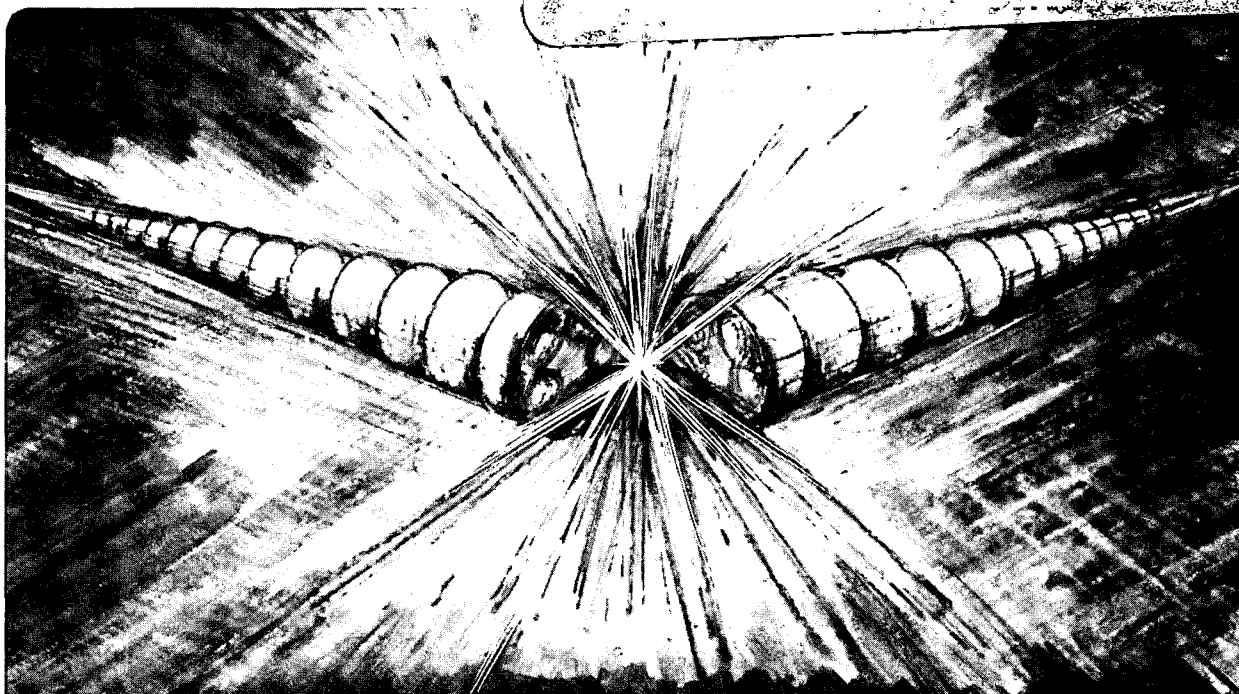
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I.G. Brown, J.E. Galvin, R.A. MacGill,  
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April 1986

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**A MINIATURE HIGH CURRENT METAL ION SOURCE\***

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April 1986

**ABSTRACT**

A small, simple ion source for the production of high brightness beams of metal ions is described. A metal vapor vacuum arc discharge is used to establish the high density plasma from which the ion beam is extracted. The source is finger-sized, and can produce pulsed metal ion beams with current up to the 10 ma range.

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A new kind of ion source has recently been described <sup>(1-4)</sup> with which high current beams of metal ions can be produced. This source makes use of a metal vapor vacuum arc as the mechanism for creating the high density metal plasma from which the ion beam is extracted. Beams of a wide range of metal species have been produced, spanning the periodic table from lithium to uranium. Beam currents of over 1 Ampere have been measured, with extraction voltage from 10 to 60 kV. The initial beam diameter is 2 cm and the normalized emittance is as low as  $0.02 \pi$  cm. mrad.

We have developed a miniaturized embodiment of the MEVVA source which is only about 1.5 cm in diameter and 6 cm in length; we've called this the MicroMEVVA ion source. The MicroMEVVA beam is of current up to about 15 ma at an extraction voltage of 15 kV and the initial beam diameter is 1 mm. We describe here the source construction and the measurements we've made to-date.

The source is simple in the extreme, being little more than an assemblage of metal and alumina tubes one within another. A photograph of the assembled MicroMEVVA is shown in Figure 1, and of the disassembled components in Figure 2. From right to left in Figure 2 the components are central trigger electrode, trigger-cathode insulator, cathode, cathode-anode insulator, anode, anode-extractor insulator, and extractor. The outer surface of the anode cylinder was machined down to a slightly smaller diameter, over that half of its length close to the extractor, so as to increase the surface path length between anode and extractor; in this way the maximum extractor voltage that could be maintained without breakdown was increased to 15 kV. The dimensions of the metal and alumina tubes were determined primarily by what was readily available out of laboratory stock; certainly the source could be miniaturized yet further if need be. The axial spacings of the components seemed to be uncritical, and were approximately as follows: the trigger electrode tip was in the plane of the end of the cathode cylinder, which in turn was several millimeters withdrawn from the anode plane; the anode-extractor gap was about 0.75 mm. The diameters of the anode hole and the extractor hole were the same, 1mm. We varied some of these dimensions and saw only small changes in the source performance. In the embodiment used here, all the metal pieces were stainless steel, excepting the cathode cylinder which was either stainless steel or titanium. The beam composition is determined by the cathode material, and to change the ion species the cathode cylinder, or at least its exposed tip, should be changed.

A schematic of the electrical circuit used to drive the source is shown in Figure 3. Typically the trigger pulse is several kilovolts in amplitude and of duration a few microseconds. The arc supply was

simply the RC discharge of a 12  $\mu$ F capacitor through a 2.5 Ohm resistor; the capacitor was charged to 100 - 200 Volts and the arc current was thus 50 - 100 Amperes. A more controlled approach would be to use an LC pulse line for the arc current supply, as has been done for MicroMEVVA's big brother, the MEVVA. Nonetheless this simple supply is adequate.

For these tests the source was located within a large vacuum chamber at a base pressure in the mid- $10^{-6}$  Torr range. Diagnostics included a magnetically-suppressed Faraday cup to measure ion beam current and a time-of-flight diagnostic to measure the ion beam composition and charge state distribution (charge-to-mass ratio of the beam components). The diagnostics have been more fully described elsewhere<sup>(3)</sup>.

Figure 4 is an oscillogram showing the ion beam current and the arc current for a typical shot. The pulse length is approximately 50 microseconds, and is determined by the time taken for the current to decay down to a value at which the arc extinguishes, about 10 Amps. The extraction voltage here was 15 kV, and the beam current about 10 ma for an arc current of a few tens of Amps. It is interesting to note that the beam current pulse shape does not precisely follow the arc current; this is due to changes in the geometry of the plasma meniscus at the extractor as the plasma density varies<sup>(5-7)</sup>. The beam noise ( $\delta i/i$ ) is about 10%, and shot-to-shot reproducibility is fair. The diameter of the Faraday cup was 5.0 cm, and the source was located about 15 cm distant from the cup; this implies that the beam current is contained within a half-angle divergence of  $10^\circ$ . Here the cathode material was stainless steel, and the dominant beam component was  $\text{Fe}^{2+}$ . The measured beam current is thus contained within an emittance of  $0.01 \pi$  cm. mrad. (normalized). This is a good emittance figure.

The electrode serving as trigger and the electrode serving as cathode may be interchanged with only slight effect on the beam output. The beam current is much the same in either case, but the current fluctuation level is somewhat greater with the center pin as cathode.

The beam current is plotted as a function of extractor voltage in Figure 5, for the case of a stainless steel cathode. The maximum current measured was 14 ma at 15 kV. Note that the scatter in the measured data points indicates the shot-to-shot variation in the extracted current. The solid curve is that calculated from the Child-Langmuir equation<sup>(7-9)</sup>.

$$j_i = 1.72 \left(\frac{Q}{A}\right)^{\frac{1}{2}} \frac{V}{d_{\text{eff}}^2} \quad \text{ma/cm}^2 \quad (1)$$

where Q and A are the charge (electronic units) and mass (amu) of the ion species, V the extraction voltage in kV, and  $d_{\text{eff}}$  the effective extractor gap in cm. It is usual to take

$$d_{\text{eff}} = d_{\text{gap}} + r_{\text{ext}} \quad (2)$$

where  $d_{\text{gap}}$  is the anode-extractor spacing and  $r_{\text{ext}}$  is the radius of the hole through which the ions are extracted from the plasma meniscus. The fit of the data to this prediction is excellent, and may be a consequence of the fact that as the arc current decays and so also the plasma density, the plasma parameters are well matched to the extraction optics at least somewhere in the decay - the extracted ion beam current maximizes at that optimum and this is the ion current that is measured.

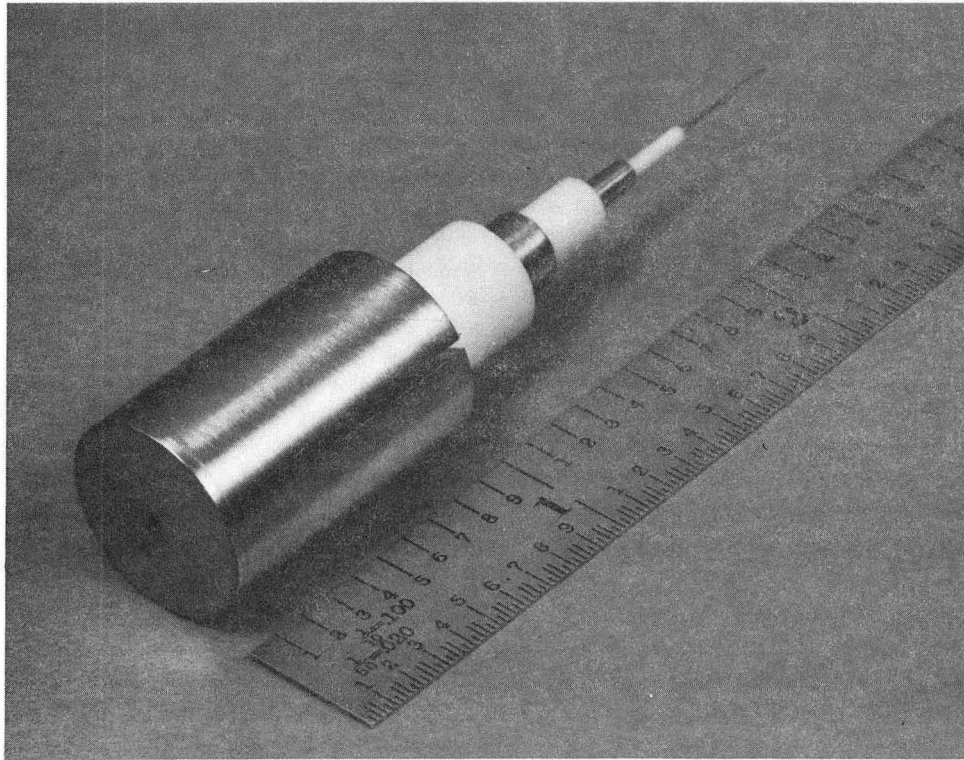
The spectral composition of the beam was measured with a time-of-flight Q/A diagnostic and typical data obtained from such a measurement are shown in Figure 6 for the case of a titanium cathode. The dominant component is  $\text{Ti}^{2+}$ , with some  $\text{Ti}^+$  and  $\text{Ti}^{3+}$ ; a small amount of  $\text{H}^+$  and  $\text{C}^+$  (or, less likely,  $\text{Ti}^{4+}$ ) contaminants can also be seen. This charge state distribution is quite similar to that produced by the MEVVA ion source at high arc current. The similarity can be taken as supporting evidence for the hypothesis that all the plasma physics, including the determination of the charge state distribution, takes place within the cathode spots.

In summary, the miniaturized embodiment of the MEVVA ion source that we've described here provides a means of producing beams of metal ions in the 10-milliampere range using a small and very simply constructed ion source.

## REFERENCES

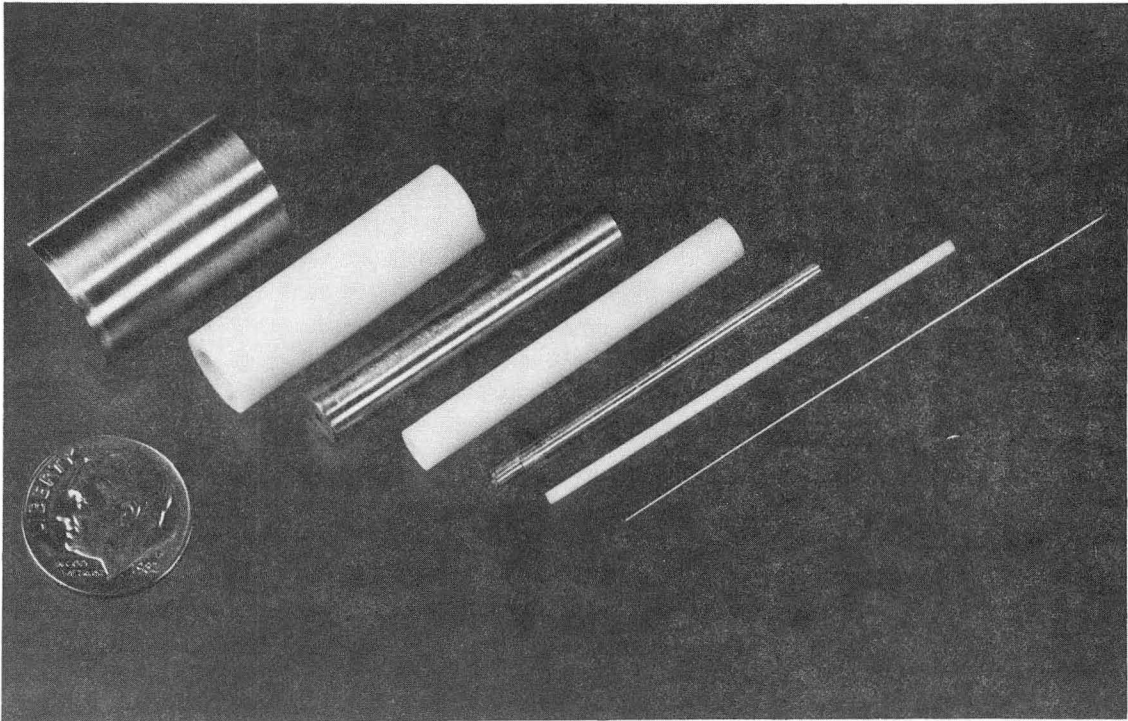
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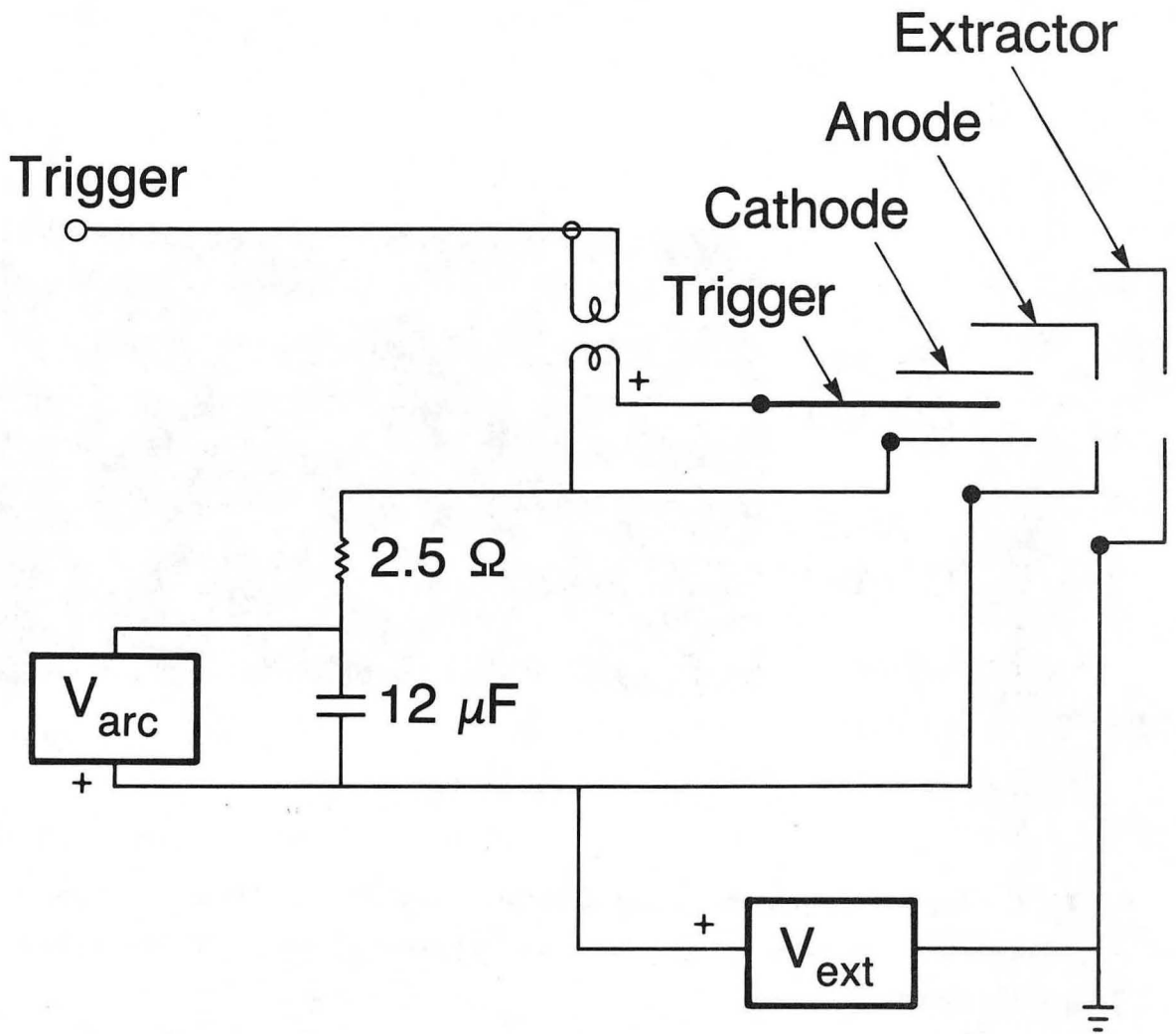
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Fig. 1 Photograph of the MicroMEVVA ion source.



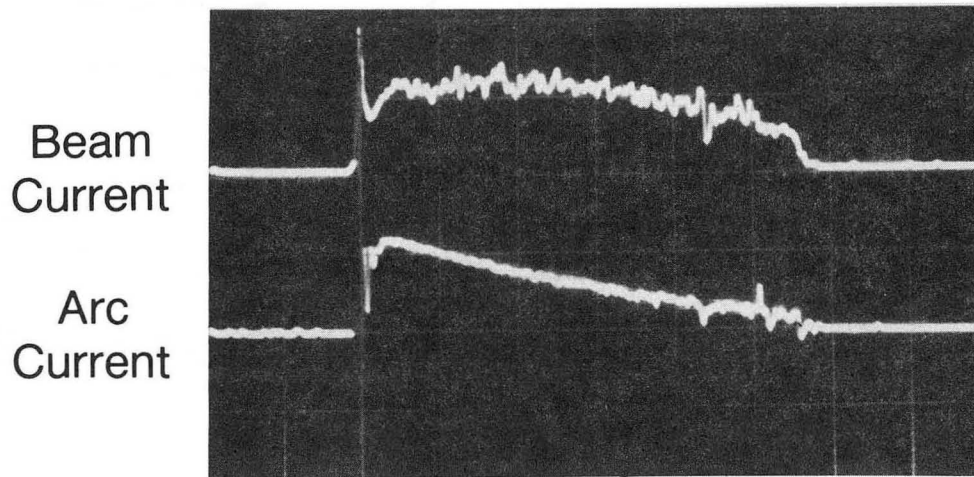
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Fig. 2 Photograph of the disassembled components of the MicroMEVVA ion source.



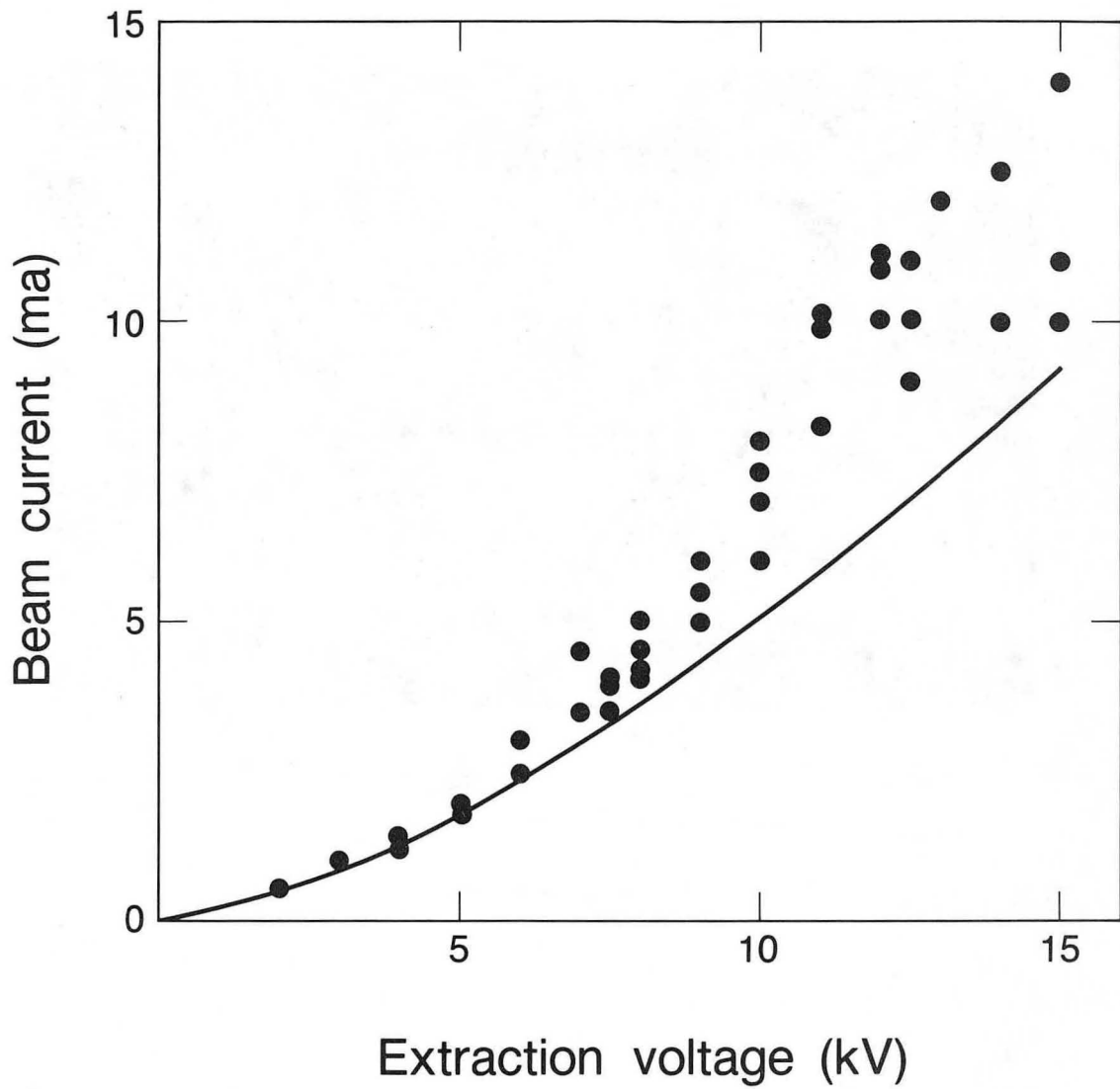
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Fig. 3 Schematic of the electrical circuit used to drive the ion source.



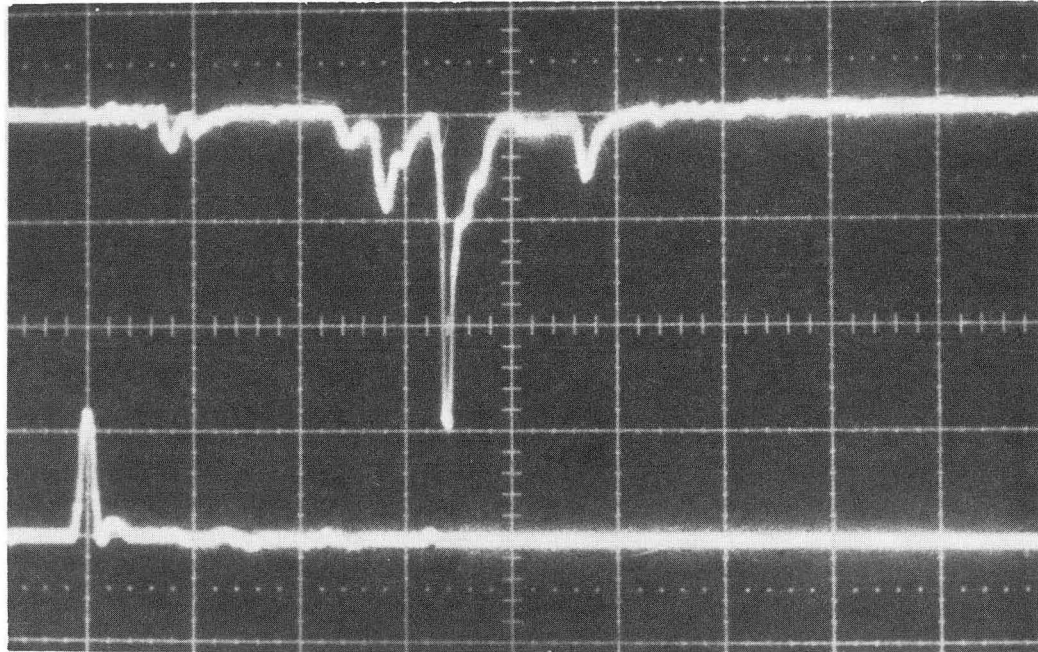
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Fig. 4 Oscillogram showing the extracted ion beam current (upper trace; 10 ma/cm) and the arc current (lower trace; 50 Amps/cm). The extractor voltage was 15 kV. Sweep speed 10  $\mu$ sec/cm.



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Fig. 5 Extracted ion beam current versus extractor voltage. The solid curve is that predicted by the Child-Langmuir theory (Equation 1) using the experimental values without any normalization.



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Fig. 6 Beam spectral analysis obtained with the time-of-flight diagnostic. Extraction voltage was 15 kV; titanium cathode; sweep speed 1  $\mu$ sec/cm.

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